


<b>INFORMATION DISCLOSURE STATEMENT</b> 	Atty. Docket No.: 110.01420101	Serial No.: 09/691,006
	Applicant(s): LEGER et al.	Confirmation No.: 4510
	Application Filing Date: October 18, 2000	Group: 2877
	Information Disclosure Statement mailed:	

## U.S. PATENT DOCUMENTS


Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
HP	5,133,601	07/28/92	Cohen et al.			
HP	5,204,734	04/20/93	Cohen et al.			
HP	5,359,622	10/25/94	Shih			
HP	5,486,701	01/23/96	Norton et al.			
HP	5,521,705	05/28/96	Oldenbourg et al.			
HP	5,602,820	02/11/97	Wickramasinghe et al.			
HP	5,754,296	05/19/98	Law			

## FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
			None				

## OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial	Document Description
HP	Absolute Ellipsometry (AE). Therna-Wave Measurement Technologies [retrieved from the Internet on 2/11/2003]. <a href="http://thermawave.com/technology/ae.htm">http://thermawave.com/technology/ae.htm</a> , 1 page.
HP	Ashkin, "History of optical trapping and manipulation of small-neutral particle, atoms and molecules," <i>IEEE Journal on selected topics in Quantum Electronics</i> , 2000; 6:841-856.
HP	Beijerbergen, et al., "Helical-wavefront laser beams produced with a spiral phaseplate," <i>Optics Comm.</i> , 1994; 112:321-327.
HP	Berger et al., "Resolution in surface plasmon microscopy," <i>Rev. Sci. Instrum.</i> , 1994; 65:2829-2836.

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HP	Biss et al., "Cylindrical vector beam focusing through a dielectric interface," <i>Optics Express</i> , 2001; 9:490-497.
HP	Courtial et al., "Rotational frequency shift of a light beam," <i>Phys. Rev. Lett.</i> , 1998; 81:4828-4830.
↑	DUV Spectroscopic Ellipsometry (SE). Therma-Wave Measurement Technologies [retrieved from the Internet on 2/11/2003]. <a href="http://www.thermawave.com/technology/duvse.htm">http://www.thermawave.com/technology/duvse.htm</a> . 1 page.
	Goodman, Introduction to Fourier Optics, 2d ed., New York, 1996; cover page, title page and table of contents, 8 pgs.
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	Kano et al., "Excitation of surface-plasmon polaritons by a focused laser beam," <i>J. Opt. Soc. Am. B</i> , 1998; 15:1381-1386.
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	Liu et al., "Vector diffraction from subwavelength optical disk structures: two-dimensional modeling of near-field profiles, far-field intensities, and detector signals from a DVD," <i>Appl. Opt.</i> , 1999; 38:3787-3797.
HP	Mansuripur, <i>The physical principles of magneto-optical recording</i> , Cambridge, Mass. 1995; cover page, title page, table of contents, 10 pgs.

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108	Minhas et al., "Ellipsometric scatterometry for the metrology of sub-0.1- $\mu$ m linewidth structures," <i>Appl. Opt.</i> , 1998; 37:5112-5115.
↑	Mirotznik et al., "Three-dimensional vector-based analysis of sub-wavelength diffractive optical elements using the finite-difference time-domain (FDTD) method," <i>Diffractive Optics and Micro-Optics</i> , Vol. 10; 1998, OSA Technical Digest Series (Optical Society of America, Washington, D.C.); 91-93.
	Mirotznik et al., "A hybrid finite element-boundary element method for the analysis of diffractive elements," <i>J. Mod. Opt.</i> , 1996; 43:1309-1321.
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108	Quabis et al., "The focus of light-theoretical calculation and experimental tomographic reconstruction," <i>Appl. Phys. B</i> , 2001; 72:109-113.

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1/88	Raether, "Surface plasmons on smooth and rough surfaces and on gratings," Springer-Verlag, Berlin, 1988. cover page, title page, table of contents, 4 pgs.
1/88	Richards et al., "Electromagnetic diffraction in optical systems II. Structure the image field in an aplanatic system," <i>Proc. R. Soc. London Ser. A</i> , 1959; 253:358-379.
↑	Rothenhäusler et al., "Surface -plasmon microscopy," <i>Nature</i> , 1998; 332:615-617.
	Sato et al., "Optical trapping of microscopic metal particles," <i>Opt. Lett.</i> , 1994; 19:1807-1809.
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	Tompkins, <i>A user's guide to ellipsometry</i> , Boston, Mass. 1993; cover page, title page, table of contents, 9 pgs.
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17P	Zhan et al., Imaging ellipsometry for high-spatial-resolution metrology, University of Minnesota, Minneapolis, MN, SPIE Proceedings, Vol. 4431, "Wave optics and VLSI photonic devices for information processing, 2001, 76.
17P	Zhan et al., "Interferometric measurement of the geometric phase in space-variant polarization manipulations," <i>Optics Communications</i> , 2002; 213:241-245.
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